

## Perpendicularly magnetized $L1_0$ -MnAl thin films for STT-MRAM

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A spin transfer torque type magnetic random access memory (STT-MRAM) has attracted considerable interest. Magnetic tunnel junctions (MTJs) using perpendicularly magnetized materials have great potential, which can develop ultra-high-density STT-MRAM. Switching current density ( $J_{c0}$ ) is directly related to saturation magnetization ( $M_s$ ) and Gilbert damping constant ( $\alpha$ ) of the ferromagnetic free layer of MTJs [1]. In order to achieve high thermal stability and low switching current density in  $p$ -MTJs, ferromagnetic materials with large perpendicular magnetic anisotropy energy ( $K_u$ ), small  $M_s$  and low  $\alpha$  are required. Here,  $L1_0$ -MnAl is a promising candidate of perpendicularly magnetized materials which satisfies the requirements for STT-MRAM [2]. However, its magnetic properties are sensitive to its crystalline structure, that is,  $L1_0$  order is necessary to obtain high  $K_u$ . In our previous works, it is expected the crystalline structure was improved by adding Co into MnAl [3]. In this work, we fabricated MnAl and  $(\text{Mn}_{1-x}\text{Co}_x)_{0.5}\text{Al}_{0.5}$  films on MgO single crystal substrate having a high  $K_u$ , small  $M_s$  and  $\alpha$ .

The film stacking structure was MgO(001)-sub./CrRu(40)/(Mn $_{1-x}$ Co $_x$ ) $_{0.5}$ Al $_{0.5}$ ( $d$ ), Mn-Al( $d$ )/Ta(5)(in nm). All the films were prepared by a magnetron sputtering system. Substrate temperature ( $T_s$ ) during deposition was varied from 200°C to 400°C and the post annealing temperature ( $T_a$ ) was varied from 200°C to 400°C. The crystal structure of  $(\text{Mn}_{1-x}\text{Co}_x)_{0.5}\text{Al}_{0.5}$  films were investigated by an X-ray diffraction (XRD). The magnetic properties and surface morphology of the films were measured by super-conductivity quantum interference device (SQUID), vibrating sample magnetometer (VSM) and atomic force microscope (AFM).

After the deposition of CrRu buffer layers, films were annealed at 650°C. A good structural property and very smooth surface morphology were exhibited. (001) and (002) peaks in XRD patterns for MnAl (50nm) films were observed at  $T_s = 350^\circ\text{C}$ . The peak intensities of MnAl were improved with increasing post annealing temperature. Both  $L1_0$ -ordered and highly (001)-oriented MnAl films were successfully fabricated. Magnetization curves are shown in Fig. 1. Bold line indicates the perpendicular and thin line indicates the in plane magnetic field directions. The value of  $K_u$  for MnAl film was  $1.2 \times 10^7$  erg/cc, small saturation magnetization,  $M_s$  of 518 emu/cc were observed at substrate temperature of 350°C.

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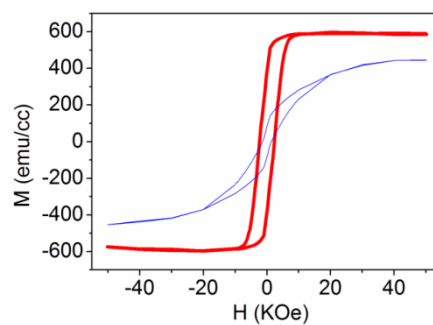


Fig. 1 The  $M$ - $H$  curve for MnAl with  $T_s = 350^\circ\text{C}$ . Bold and thin lines indicate perpendicular and in-plane directions of magnetic field.